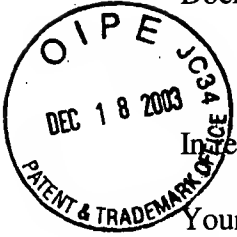


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2823

Docket No.: 005916 USA/FPS/MMCS/MC

PATENT/OFFICIAL



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Young Joseph PAIK

Serial No. 09/998,384

Filed: November 30, 2001

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Group Art Unit: 2812

Examiner:

For: FEEDFORWARD AND FEEDBACK CONTROL FOR CONDITIONING OF
CHEMICAL MECHANICAL POLISHING PAD

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Honorable Commissioner for Patents
Alexandria, VA 22313-1450

Sir:

In accordance with the provisions of 37 C.F.R. 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the documents listed on the attached form PTO-1449. It is respectfully requested that the documents be expressly considered during the prosecution of this application, and that the documents be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This Information Disclosure Statement is being filed within three months of the U.S. filing date OR before the mailing date of a first Office Action on the merits. No certification or fee is required.

This submission does not constitute a representation that a search has been made or that no better art exists and does not constitute an admission or representation that any of the listed documents is material or constitutes prior art. If it should be determined that any of the listed documents does not constitute prior art under the United States law, Applicants reserve the right

Serial No. 09/998,384

to present to the Office the relevant facts and law regarding the appropriate status of such document.

No certification or fee is believed to be required. However, the Commissioner is hereby authorized to charge any additional fees should any be required for this submission, or credit any overpayment to deposit account no. 08-0219.

Respectfully submitted,

HALE AND DORR LLP



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Date: 12/16/03

**INFORMATION DISCLOSURE
CITATION IN AN
APPLICATION
(PTO-1449)**



ATTY. DOCKET NO.
005916
USA/FPS/MMCS/MC

SERIAL NO.
09/998,384

APPLICANT
Young Joseph PAIK

FILING DATE
November 30, 2001

GROUP
2812

U.S. PATENT DOCUMENTS

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	4,209,744	06/24/80	Gerasimov et al.			03/27/78
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	5,427,878	06/27/95	Corliss			05/16/94
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	6,563,308	05/13/03	Nagano et al.			03/27/01
	6,587,744	07/01/03	Stoddard et al.			06/20/00

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						Yes	No
	WO 01/11679	02/15/01	WIPO			X	
	WO 01/080306	10/25/01	WIPO			X	

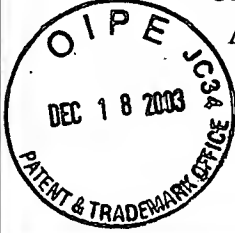
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	Miller, G. L., D. A. H. Robinson, and J. D. Wiley. July 1976. "Contactless measurement of semiconductor conductivity by radio frequency-free-carrier power absorption." <i>Rev. Sci. Instrum.</i> , Volume 47, No. 7. pp. 799 – 805.
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	2000. "Microsense II Capacitance Gaging System." www.adetech.com .

EXAMINER

DATE CONSIDERED

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

INFORMATION DISCLOSURE CITATION IN AN APPLICATION (PTO-1449) 				ATTY. DOCKET NO. 005916 USA/FPS/MMCS/MC		SERIAL NO. 09/998,384	
				APPLICANT Young Joseph PAIK			
				FILING DATE November 30, 2001		GROUP 2812	
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	"NanoMapper FA factory automation wafer nanotopography measurement." http://www.phase-shift.com/nanomapperfa.shtml .						
EXAMINER				DATE CONSIDERED			

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